

ABSTRACT

A front opening wafer container has a container portion with a transparent shell and a door to close the open front. The container portion has a machine interface on the bottom of the shell, such as a kinematic coupling, and a receptacle at the top of the shell to receive an accessories, in particular a robotic lifting flange or an adaptor plate. The adaptor plate will ideally have a cooperating machine interface portions to allow stacking of the wafer carriers. The receptacle has, in preferred embodiments, sliding support guides with undercut portions for retention of the robotic lifting flange or the adaptor plate . The accessory will ideally have a detent positioned on the accessories to releasably lock said accessory in place on the container portion.